

ABSTRACT

PROCESSING TOOL MONITORING

A monitoring apparatus for monitoring at least one processing tool, a method
5 and computer program product are disclosed. The monitoring apparatus for
monitoring at least one processing tool during processing of an effluent
stream from a semiconductor processing tool, comprises: reception logic
operable to receive processing characteristic data generated during the
processing of the effluent stream; segregation logic operable to segregate the
10 processing characteristic data into contributing processing characteristic data
associated with contributing periods which contribute to a condition of the at
least one processing tool and non-contributing processing characteristic data
associated with non-contributing periods which fail to contribute to the
condition; and fault logic operable to utilise the contributing processing
15 characteristic data and to exclude the non-contributing processing
characteristic data when determining a status of the condition. In this way,
only data generated during periods which contribute to the condition of the
tool is used when determining a status of the condition of that tool. Other data
generated during periods which do not contribute to that condition are ignored
20 or omitted so that an accurate assessment of the status of the condition of the
tool can be determined. This helps to provide an accurate and more reliable
assessment of the status of the condition of the tool.

(Figure 1)